

## PATENT ABSTRACTS OF JAPAN

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(21)Application number : 11-069880 (71)Applicant : SUMITOMO BAKELITE CO LTD  
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#### (54) PRODUCTION OF NOVOLAK RESIN FOR PHOTOBEST

(57) Abstract:

**PROBLEM TO BE SOLVED:** To provide a method for producing a novolak resin for a positive-type photoresist, capable of sufficiently controlling its dissolving speed in alkali, and consequently forming such an extremely fine pattern that the line width is 0.30  $\mu$ m.

**SOLUTION:** This method for producing a novolak resin for a photoresist comprises reacting a phenol with an aldehyde using an aromatic hydrocarbon or an aliphatic hydrocarbon as a solvent at a temperature of 150° C in a pressure vessel, then subjecting the reaction product to crosslinking reaction using a crosslinking agent, such as the aldehyde or a dimethyol compound derived from the phenol.

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